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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10075967	FILING DATE 02/14/2002	CLASS 118	SUBCLASS 345.1	GAU 1763	EXAMINER MOORE
**APPLICANTS: Sun Jennifer; Wu Shun; Thach Senh; Kumar Ananda; Wu Robert; Wang Hong; Lin Yixing; Stow Clifford;					
**CONTINUING DATA VERIFIED:					
** FOREIGN APPLICATIONS VERIFIED:					
PG-PUB	DO NOT PUBLISH	RESCIND			
Foreign priority claimed 35 USC 119 conditions met		<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO 005120 USA/ETCH/IBSS	
Verified and Acknowledged Examiners's initials					
TITLE : Yttrium oxide based surface coating for semicondctor IC processing vacuum chambers U.S.DEP'T. OF COMM./PAT.& TM-PTO-436L(Rev. 12-94)					

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NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs.Drwg.
<input type="checkbox"/> TERMINAL		Application Examiner		
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